

FORM PTO-1449 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEAttorney Docket No.:
P2000,0361Applic. No.
10/609,464

 INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(37 CFR 1.98(b))

Applicant

Wolfgang Dickenscheid, et al.

Filing Date
June 27, 2003Group Art Unit
2125

U.S. PATENT DOCUMENTS

| EXAMINER INITIALS | | PATENT NO. | DATE | PATENTEE | CLASS | SUB CLASS | FILING DATE |
|----------------------|---|------------|------|----------|-------|--------------|----------------|
| | A | | | | | | |
| | B | | | | | | |
| | C | | | | | | |
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FOREIGN PATENT DOCUMENT

| | | DOCUMENT NO. | DATE | COUNTRY | CLASS | SUB CLASS | TRANSL. YES NO |
|--|---|--------------|------|---------|-------|--------------|---------------------|
| | J | | | | | | |
| | K | | | | | | |
| | L | | | | | | |
| | M | | | | | | |
| | N | | | | | | |

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

| | | |
|--|---|--|
| | O | 1997 Proceedings Second International Chemical-Mechanical Polish (C.M.P.) for ULSI Multilevel Interconnection Conference (CMP-MIC). "A Mechanical Model for Dram Dielectric Chemical-Mechanical Polishing Process." Catalog No. 97ISMIC-200P, Library of Congress No. 89-644090, February 13-14, 1997, Santa Clara, CA, pp. 259-265. |
| | P | |

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.